



520.43429X00

Applicants: Minoru YOSHIDA et al.  
Serial No.: 10/765,920  
Filed: January 29, 2004  
Title: PATTERN DEFECT INSPECTION METHOD AND ITS APPARATUS  
Group: 2878  
Examiner: ZETTL, Mary E.  
Confirmation No.: 2671

**AMENDMENT**

**Mail Stop: AMENDMENT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

February 13, 2006

Sir:

In response to the Office Action dated October 13, 2005, please amend the above-identified application as listed below and as set forth on the following pages:

**Amendments** to the claims begin on page 2;

**Remarks** are included beginning on page 13; and

**Authorization** is included on page 19.